

Substitute for form 1449/PTO (Revised 07/2007)  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (Use as many sheets as necessary)				<b>Complete if Known</b>	
				Application Number	10/583,570
				Filing Date	March 5, 2007
				First Named Inventor	DeSimone
				Art Unit	1791
				Examiner Name	Not Yet Assigned
Sheet	1	of	10	Attorney Docket Number	035052/338899

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				Application Number	10/583,570
				Filing Date	March 5, 2007
				First Named Inventor	DeSimone
				Art Unit	1791
				Examiner Name	Not Yet Assigned
Sheet	9	of	10	Attorney Docket Number	035052/338899

OTHER DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	English Language Translation Attached
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